Thijs Roskamp 2024 QuMat year meeting Enschede 11/11/2024

SQUID on cantilever probes based on corner lithography

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Scanning SQUID microscopy

Scanning SQUID microscopy (SSM) spatially resolves magnetic flux from a surface

Persky et al. Annu. Rev. of Condens. Matter Phys. **13**: 385-405 (2022)



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SQUID:

Superconducting

QUantum Interference

Device

Magnetic flux threading the SQUID loop is related to the voltage measured across it.



SSM provides high-field sensitivity and noninvasiveness

Conventional scanning SQUID



- SQUID chip with pickup loop →
 ~1-5 µm
- Waferscale fabrication and highly reproducible
- Freedom to tune the SQUID washer and integration of fieldand modulation coils

Limited by planar structure in sample surface-pickup loop height

SQUID at the apex of a tip

Scanning SQUID 2.0: Move the SQUID from the substrate plane to a tip

2010: SQUID-on-tip (SOT)

(Zeldov group, Weizmann Institute of Science, Israel)



Finkler *et al. Nano Lett.* **10**: 1046-1049 (2010)

- Three-step thermal evaporation of Nb,
 Pb, Al etc. on pulled quartz tube
- 1. Loop diameters down to 50 nm
- 2. Tip-sample distance \sim 50-200 nm (QTF)

SQUID on AFM cantilever

- Power of AFM scanning/height control
- Multi-function probe: Magnetometry and Topography





- Wafer scale templates using conventional silicon processing and corner lithography
- Simple deposition of superconductor by magnetron sputtering
- Focused-ion beam milling to SQUIDs

Corner Lithography



Berenschot et al. Small 8: 3823-3831 (2012)

- I. Template preparation
- II. Deposition of conformal layer
- III. Time-controlled selective isotropic etching of layer

Corner lithography

- Timed etching to perform corner lithography and keep nitride in
 - all concave corners





A SQUID on a cantilever (iii)

- Magnetron sputtering of Ti/Nb/Pd
- Superconducting at 8.4 K; $I_c \sim$ several mA





Our idea

Wafer scale templates using conventional silicon processing and corner lithography

Simple deposition of superconductor by magnetron sputtering by exploiting shadow effects

 Focused-ion beam milling to create weak links and loops at the apex of corner lithography wireframe pyramids

Weakening the superconductor: FIB



- FIB: Focused Ion Beam
 - i. Gallium ions etch away material
 - ii. Small beam width ~ 15 nm
- FIB and superconductors
 - i. Modify Current-Phase Relation \rightarrow weak links





A SQUID on a cantilever (i)

- FIB \rightarrow Dayem bridges of L x W ~ 40 x 40 nm
- SQUID oscillations: $\Delta B = 2.1 \text{ mT} \rightarrow a = \sqrt{\frac{\Phi_0}{\Delta B}} = 992 \text{ nm}$





A SQUID on a cantilever (ii)

- Different tip structures possible
- FIB \rightarrow Entire SQUID



SQUID oscillations:
$$\Delta B = 37 \text{ mT}$$

d = $2\sqrt{\frac{\Phi_0}{\pi\Delta B}} = 270 \text{ nm}$





Conclusion and Outlook

- Reliable nanofabrication of 3D pyramid nanowireframe and integration onto conventional silicon nitride cantilever
- Successful fabrication of superconducting probe
- Successful FIB-milling of SQUIDs and Dayem bridges at the apex of the probe

- Sub-100 nm SQUID loops; Much freedom to tune loop sizes
- Possibility for modulation or field coil
- Other superconductors; HTS?





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QuMat Materials for the Quantum Age

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